

03500.015110.1



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Takako YAMAGUCHI et al.

Application No.: 10/630,792

Filed: July 31, 2003

For: PATTERN-FORMING APPARATUS
USING A PHOTOMASK (As Amended)

) Examiner: K. C. Gutierrez

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) Group Art Unit: 2851

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) Confirmation No.: 7876

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) Allowed: February 15, 2006

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) April 17, 2006

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Mail Stop RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application as follows: